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August 3, 2006

Julie Goldberg
Nanometrics Incorporated
1550 Buckeye Drive
Milpitas, CA 95035-7418

Re: U.S. Patent Application: "Method for Automatically De-Skewing of Multiple Layer Wafer for Improved Pattern Recognition"
Inventors: Jian Zhou et al.
Serial No.: 09/974,721
Filing Date: October 9, 2001
Our Reference: NAN050 US

FOR YOUR FILES

Dear Julie:

Enclosed for your files are copies of the following:

1. Request for Continued Examination (RCE) Transmittal; and
2. Response to Office Action.

These materials were mailed via Facsimile to the United States Patent and Trademark Office on August 3, 2006. Please let me know if there are any questions or comments.

Sincerely,



Michael J. Halbert

MJH/mh
Enclosures